## WHAT IS CLAIMED IS:

1	1. An apparatus for measuring physical properties of a plurality of material		
2	samples, the apparatus comprising:		
3	a moveable sample holder for containing the plurality of material samples;		
4	at least one probe for mechanically perturbing the material samples, the at least one		
5	probe having an end;		
6	at least one actuator connected to the moveable sample holder for translating the		
7	material samples in a direction normal to the end so that the material samples contact the at		
8	least one probe; and		
9	at least one sensor for monitoring the response of the material samples to mechanical		
10	perturbation by the at least one probe.		
1	2. The apparatus of claim 1, wherein the sensor includes force sensors		
2	mechanically linked to the probes.		
1	3. The apparatus of claim 2, further comprising shafts that mechanically link the		
2	force sensors to the probes.		
1	4. The apparatus of claim 3, wherein each of the shafts includes a rigid core and		
2	an insulating outer sheathing.		
1	5. The apparatus of claim 3, further comprising flexure strips attached to each of		
2	the shafts for aligning the probes with the material samples.		
1	6. The apparatus of claim 3, further comprising an isolation block module for		
2	separating the probes and the force sensors.		
1	7. The apparatus of claim 6, wherein the isolation block module has first and		
2	7. The apparatus of claim 6, wherein the isolation block module has first and second surfaces and cylindrical apertures for containing the shafts, the cylindrical apertures		
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3	extending from the first surface to the second surface.		
1	8. The apparatus of claim 7, further comprising flexure strips for aligning the		
2	probes with the material samples, each of the flexure strips attached to the shafts and walls of		
3	the cylindrical apertures of the isolation block module.		
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1	9.	The apparatus of claim 1, wherein the actuator is a piezoelectric stack.
1	10.	The apparatus of claim 9, wherein the actuator includes a motorized translation
2	slide linked to	o the piezoelectric stack
1	11.	The apparatus of claim 1, further comprising a control system for regulating
2	environmenta	ol conditions of the material samples.
1	12.	The apparatus of claim 8, wherein the control system includes an
2	environmenta	al chamber enclosing the material samples.
1	13.	The apparatus of claim 1, wherein the force sensors are mounted on at least
2	one flex circu	uit.
1	14.	The apparatus of claim 13, wherein the force sensors are mounted on first and
2	second flex c	ircuits, the first flex circuit disposed above the second flex circuit.
1	15.	The apparatus of claim 1, wherein the force sensors are pre-loaded to measure
2	compressive	and tensile forces on the probes.
1	16.	The apparatus of claim 1, further comprising a data logger for recording
2	responses fro	m the sensor.
1	17.	The apparatus of claim, wherein each of the probes includes at least one test
2	fixture remov	reably mounted on a probe base, the probe base distal to the ends of the probes.
1	18.	The apparatus of claim 17, wherein the at least one test fixture is magnetically
2	coupled to th	
1	10	The amounting of claim 17 wherein the at least one test fixture has a blunt and
1 2	19.	The apparatus of claim 17, wherein the at least one test fixture has a blunt end g the material samples.
	ioi comacini	5 die material samples.
1	20.	The apparatus of claim 17, wherein the at least one test fixture has a sharp end
2	for contacting	g the material samples.

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the second reservoir.

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the material samples.

The apparatus of claim 17, wherein the test fixture is bonded to at least one of

The apparatus of claim 21, wherein the test fixture is oriented to either extend

least one physical property of at least eight samples simultaneously.

The apparatus of claim 1, wherein the apparatus is capable of measuring at

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one of the perforated plates.

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The apparatus of claim 1, wherein the apparatus is capable of measuring at 1 31. 2 least one physical property of at least forty-eight samples simultaneously. 1 32. The apparatus of claim 1, wherein the apparatus is capable of measuring at 2 least one physical property of at least ninety-six samples simultaneously. 1 33. The apparatus of claim 1, wherein the apparatus is capable of measuring at 2 least two different physical properties of the samples simultaneously. 34. 1 The apparatus of claim 33, wherein the test methods used to measure said at 2 least two different physical properties are selected from the group consisting of flexure, uniaxial extension, biaxial compression, shear, indentation, stress and strain at failure, 3 toughness, tack, loop tack, viscosity, melt flow indexing, storage modulus, and loss modulus. 35. A system for screening a combinatorial library of materials by measuring 1 2 physical properties of the materials, the system comprising: 3 an array of a plurality of material samples; at least one probe for mechanically perturbing the plurality of material samples, the at least one probe having an end; at least one actuator for translating the plurality of material samples in a direction 7 normal to the end so that the material samples contact the at least one probe; and at least one sensor for monitoring the response of the plurality of material samples to 8 9 mechanical perturbation by the at least one probe. The system of claim \$15, wherein the array of material samples comprises a 1 36. 2 flexible substrate coated with materials at discrete predefined regions. 37. The system of claim \$6, further comprising a pair of perforated plates, wherein 1 2 the flexible substrate is either sandwiched between the perforated plates or bonded to at least

rigid substrate coated with materials at discrete predefined regions.

The system of claim 35, wherein the array of material samples comprises a

The system of claim 38, wherein the rigid substrate has a low coefficient of

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friction with respect to the material samples.

of the materials simultaneously with probes; and

mechanically perturbing an array of a plurality of materials by contacting at least two

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- monitoring the response of the materials to the mechanical perturbations. 4
- 50. The method of claim 49, wherein monitoring the response of the materials to 1 2 the mechanical perturbations includes measuring forces exerted on the probes by the material 3 samples as functions of displacement between the probes and the materials.
  - 51. The method of claim 50, wherein monitoring the response of the material samples to the mechanical perturbations includes measuring forces exerted on the probes by the materials as functions of time.
    - 52. The method of claim 49, further comprising relating the response of the array of materials to Young's modulus, hardness, viscosity, storage modulus, or loss modulus.
    - 53. The method of claim 49, wherein the method is capable of screening at least twelve materials simultaneously.
    - 54. The method of claim 49, wherein the method is capable of screening at least forty-eight materials simultaneously.
    - 55. The method of claim 49, wherein the method is capable of screening at least ninety-six materials simultaneously.
  - The apparatus of claim 17, wherein the movable sample holder comprises a 56. frame and at least two cups, which are slidable mounted to the frame, and at least two intersecting substrate pieces, with one of said pieces being attached to the frame and the other of said pieces being attached to the cups.
    - The apparatus of claim 17, wherein the moveable sample holder comprises a 57. frame and at least two weights, positioned in receptacles in the frame, with a known surface positioned parallel to the at least one end on which the material sample is deposited.
  - 58. The apparatus of claim 17, wherein the test fixture comprises a spring poppet with a cap, said cap having a known surface positioned parallel to the plurality of materials samples.